

# UNITED STATES PATENT AND TRADEMARK OFFICE

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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
09/507,465	02/22/2000	Rodney C. Langley	M4065.0018/P018-A	2423	
24998	7590 02/04/2003				
DICKSTEIN SHAPIRO MORIN & OSHINSKY LLP			EXAMINER		
2101 L STRE	ET NW DN, DC 20037-1526	ANDERSON, MATTHEW A			
WASHINGTO	JN, DC 20037-1320				
			ART UNIT	PAPER NUMBER	
			1765	21	
			DATE MAILED: 02/04/2003		

Please find below and/or attached an Office communication concerning this application or proceeding.

•	Application No.	Applicant(s)				
	09/507,465	LANGLEY ET AL.				
Office Action Summary	Examiner	Art Unit				
	Matthew A. Anderson	1765				
The MAILING DATE of this communication app Period for Reply	pears on the cover sheet	with the correspondence address				
A SHORTENED STATUTORY PERIOD FOR REPL' THE MAILING DATE OF THIS COMMUNICATION.  - Extensions of time may be available under the provisions of 37 CFR 1.1 after SIX (6) MONTHS from the mailing date of this communication.  - If the period for reply specified above is less than thirty (30) days, a repl - If NO period for reply is specified above, the maximum statutory period - Failure to reply within the set or extended period for reply will, by statute - Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).  Status	36(a). In no event, however, may y within the statutory minimum of will apply and will expire SIX (6) No. cause the application to become	v a reply be timely filed thirty (30) days will be considered timely. IONTHS from the mailing date of this communic ABANDONED (35 U.S.C. § 133).	≃ation.			
1)⊠ Responsive to communication(s) filed on <u>15 I</u>	<u>November 2002</u> .					
2a)⊠ This action is <b>FINAL</b> . 2b)□ Th	is action is non-final.					
3) Since this application is in condition for allowationsed in accordance with the practice under			its is			
Disposition of Claims						
4) Claim(s) 10,12-16 and 26 is/are pending in the						
4a) Of the above claim(s) is/are withdraw	wn from consideration.					
<u> </u>	5) Claim(s) is/are allowed.					
·	) Claim(s) 10 and 12-16, 26 is/are rejected.					
7) Claim(s) is/are objected to.	r alastian raquirament					
8) Claim(s) are subject to restriction and/o Application Papers	r election requirement.					
9) The specification is objected to by the Examine	er.					
10)⊠ The drawing(s) filed on 22 February 2000 is/are	e: a)⊠ accepted or b)□	objected to by the Examiner.				
Applicant may not request that any objection to the	e drawing(s) be held in ab	eyance. See 37 CFR 1.85(a).				
11)☐ The proposed drawing correction filed on	_ is: a)☐ approved b)☐	disapproved by the Examiner.				
If approved, corrected drawings are required in re	ply to this Office action.					
12) The oath or declaration is objected to by the Ex	aminer.					
Priority under 35 U.S.C. §§ 119 and 120						
13) Acknowledgment is made of a claim for foreign	n priority under 35 U.S.	C. § 119(a)-(d) or (f).				
a)☐ All b)☐ Some * c)☐ None of:						
<ol> <li>Certified copies of the priority document</li> </ol>	s have been received.					
2. Certified copies of the priority document	s have been received ir	Application No				
<ul> <li>3. Copies of the certified copies of the prior</li> <li>application from the International Bu</li> <li>* See the attached detailed Office action for a list</li> </ul>	reau (PCT Rule 17.2(a)	)).	<b>;</b>			
14) Acknowledgment is made of a claim for domesti	c priority under 35 U.S.	C. § 119(e) (to a provisional appli	cation).			
a) ☐ The translation of the foreign language pro	* *					
Attachment(s)	. <del>-</del>	- <del>-</del>				
1) Notice of References Cited (PTO-892) 2) Notice of Draftsperson's Patent Drawing Review (PTO-948) 3) Information Disclosure Statement(s) (PTO-1449) Paper No(s)	5) Notice	ew Summary (PTO-413) Paper No(s) of Informal Patent Application (PTO-152)				

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#### **DETAILED ACTION**

### Claim Rejections - 35 USC § 102/103

1. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

- (b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.
- 2. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
  - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 3. Claims 10, 12-13, 16, 26 are rejected under 35 U.S.C. 102(b) as anticipated by or, in the alternative, under 35 U.S.C. 103(a) as obvious over Helms et al. (US 4,869,801).

An embodiment represented in Fig. 4 of Helms and described in detail in col. 4 lines 13+ anticipates the present invention. Disclosed is a RIE (i.e. a plasma) etching apparatus and method. The wafer is placed on a chuck plate which is coupled to a pedestal with a central hollow shaft. The chuck and pedestal combine to define cooling passages (73, 74, 75 in Fig. 4) connected in fluid communication with the hollow shaft.

The pedestal is rotated by the motor (84). The apparatus is described as used in a RIE chamber with cooling and rotation. In Figs. 4 is depicted a method of removing the

wafer by push rod (51) coupled to a lift actuator (40) and spider (46 with pins 47, 47').

The actuated push rods push up and the lift pins (47) lift the wafer from the chuck. The

hollow cooled shaft of the pedestal (Fig. 4, 45) moves in response to actuation of the

wafer lift mechanism

It is unclear if the cooling medium is limited to only a liquid.

However, it would have been obvious to one of ordinary skill in the art at the time of the present invention to use a gas coolant since Helms et al. suggests as much in col. 3 line 1.

In respect to claims, 10, 26, one of ordinary skill in the art would have found it obvious that the hollow shaft of Helms would have been at least "capable of one-way communication" of gaseous coolant to the coolant chamber because all such hollow shafts are inherently "capable of one-way communication depending on the use of pumps or pressure gradients.

## Claim Rejections - 35 USC § 103

4. Claim 14, 15 is rejected under 35 U.S.C. 103(a) as being unpatentable over Helms et al. as applied to the above claims, and further in view of Saeki et al. (US 5460684) and Nozawa et al. (US 5290,381).

Helms is described above.

Helms does not explicitly disclose an electrostatic chuck.

Saeki et al. discloses in the abstract an electrostatic chuck in a plasma apparatus used in a plasma etching process.

It would have been obvious to one of ordinary skill in the art at the time of the present invention to combine the Helms et al. and the Saeki et al. references because then the placement of the wafer would be even more accurate than as required by Helms et al. since the electrostatic chuck would preclude movement during processing.

The combination does not disclose the optimization of process parameters.

Nozawa et al. discloses a plasma etching apparatus and discloses using certain set process parameters in col. 7. The parameters specified include gas flow and wafer temperature.

It would have been obvious to one of ordinary skill in the art at the time of the present invention to combine Nozawa et al. with the above combination because then more control over the etching profile produced (see Figs. 5-7 of Nozawa et al.) would be expected.

## Response to Arguments

5. Applicant's arguments filed 11/15/2002 have been fully considered but they are not persuasive.

The argument that the hollow shaft is not capable of one way communication of a gaseous coolant to the coolant chamber is not logical. All hollow shafts are at least

inherently capable of accommodating one-way movement of gas barring some other structure within it. Helms et al. suggests gaseous coolants in col. 3 lines 1-5. The rejection is stated as a USC 102/103 rejection and not as a pure USC 102.

The argument that Fig 4 somehow shows that Helms is incapable of one way communication is not convincing. Inlet and outlet flows are not through the same tubes and thus are only in one direction – i.e. that of further toward the exhaust were the hot coolant is removed from the system.

The claim that the coolants do not flow through a central bore of a shaft in Figs. 2 and 3 of Helms is not convincing. The examiner notes that Fig. 4 shows the central hollow shaft arrangement claimed.

The argument that Helms is a suspect reference is not convincing. Since Helms has been published as a United States Patent, the examiner gives full confidence to its teachings. The examiner notes that Fig. 2 shows unmarked passages on the left side of the shaft mirroring the gas introduction lines. These, to the rational engineering observer, would be seen as outlet lines.

The argument that claims 14-15 are allowable because Helms is not a good reference is not convincing. The examiner has presented a motivation for the combination on which the rejection was made and stands by his earlier assessment concerning these claims.

#### **Conclusion**

THIS ACTION IS MADE FINAL. Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the mailing date of this final action.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Matthew A. Anderson whose telephone number is (703) 308-0086. The examiner can normally be reached on M-Th, 6:30-5.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Benjamin Utech can be reached on (703) 308-3836. The fax phone numbers for the organization where this application or proceeding is assigned are (703) 872-9310 for regular communications and (703) 872-9311 for After Final communications.

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Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is (703) 308-0661.

MAA

February 1, 2003

BENJAMIN L. UTECH SUPERVISORY PATENT EXAMINER

TECHNOLOGY CENTER 1700